

Attorney Docket: 081468-0306781  
Client Reference: P-0381.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:  
JOERI LOF ET AL.



Confirmation Number: 5288

Application No.: 10/705,805

Group Art Unit: 2851

Filed: November 12, 2003

Examiner: Peter B. Kim.

Title: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

**REQUEST FOR RETURN OF PTO-1449**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants respectfully request that the Examiner return an initialed copy of the PTO-1449 form that was filed on November 12, 2003. A copy of the PTO-1449, the cited references, and the stamped USPTO receipt are attached for the Examiner's convenience.

Applicants respectfully request that the Examiner initial, sign and date the references on the attached PTO-1449 form dated November 12, 2003, and return the form to the undersigned.

Respectfully submitted,

Date: March 8, 2006

Jean-Paul G. Hoffman  
Registration No. 42663  
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Customer No. 00909

Atty.  
Dkt. No.

M#

Client Ref.

306781

P-0381.010-US

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**



Applicant: Joeri LOF et al.

Appln. No.: Unknown

Filing Date: November 12, 2003

Examiner: Unknown

Group Art Unit: Unknown

Date: November 12, 2003

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**U.S. PATENT DOCUMENTS**

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	3,573,975	04/1971	Dhaka et al.	117	212	
	BR	3,648,587	03/1972	Stevens	95	44	
	CR	4,346,164	08/1982	Tabarelli et al.	430	311	
	DR	4,396,705	08/1983	Akeyama et al.	430	326	
	ER	4,480,910	11/1984	Takanashi et al.	355	30	
	FR	4,509,852	04/1985	Tabarelli et al.	355	30	
	GR	5,040,020	08/1991	Rauschenbach et al.	355	53	
	HR	5,121,256	06/1992	Corle et al.	359	664	
	IR	5,610,683	03/1997	Takahashi	355	53	
	JR	5,715,039	02/1998	Fukuda et al.	355	53	
	KR	5,825,043	10/1998	Suwa	250	548	
	LR	5,900,354	05/1999	Batchelder	430	395	
	MR	6,191,429	02/2001	Suwa	250	548	
	NR	6,560,032	05/2003	Hatano	359	656	

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		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	OR	WO 99/49504	09/1999	PCT	Fukami et al.	X		X	
	PR	EP 0023231	02/1981	Europe	Tabarelli et al.	X			
	QR	EP 0418427	03/1991	Europe	Miyake	X		X	
	RR	EP 1039511	09/2000	Europe	Murakimi et al.	X		X	
	SR	DD 224448	07/1985	German	Hesse et al.		X		
	TR	DD 242880	02/1987	German	Kuch		X		
	UR	FR 2474708	07/1981	France	Letellier		X		
	VR	JP 62-065326	03/1987	Japan	Moriuchi	X			
	WR	JP 62-121417	06/1987	Japan	Nakazawa	X			
	XR	JP 63-157419	06/1988	Japan	Nakasuji	X			

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

YR	EP Search Report for EP 02257938 dated September 25, 2003				
ZR	M. Switkes et al., "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001				
AAR	M. Switkes et al., "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356				
BBR	M. Switkes et al., "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002				

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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	306781	P-0381.010-US

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Joeri LOF *et al.*

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Examiner: Unknown Group Art Unit: Unknown

Date: November 12, 2003

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	CCR 6,603,130	08/2003	Bisschops <i>et al.</i>	250	492.1	
	DDR 6,633,365	10/2003	Suenaga	355	53	
	EER 2002/0163629	11/2002	Switkes <i>et al.</i>	355	53	
	FFR 2003/0123040	07/2003	Almogly	355	69	
	GGR 2003/0174408	09/2003	Rostalski <i>et al.</i>	359	642	
	HHR					
	IIR					
	JJR					
	KKR					
	LLR					
	MMR					
	NNR					
	OOR					
	PPR					

## FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	QQR JP 04-305915	10/1992	Japan	Ozeki <i>et al.</i>	X			
	RRR JP 04-305917	10/1992	Japan	Ozeki <i>et al.</i>	X			
	SSR JP 06-124873	05/1994	Japan	Takahashi	X		X	
	TTR JP 07-220990	08/1995	Japan	Fukuda <i>et al.</i>	X			
	UUR JP 10-228661	08/1998	Japan	Kurokawa	X			
	VVR JP 10-255319	09/1998	Japan	Suenaga <i>et al.</i>	X			
	WWR JP 10-303114	11/1998	Japan	Suwa	X		X	
	XXR JP 10-340846	12/1998	Japan	Kudo	X		X	
	YYR JP 2001-091849	04/2001	Japan	Aizaki <i>et al.</i>	X			
	ZZR							

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AAAR	B.J. Lin, "Drivers, Prospects and Challenges for Immersion Lithography", TSMC, Inc., September 2002
BBBR	B.J. Lin, "Proximity Printing Through Liquid", IBM Technical Disclosure Bulletin, Vol.20, No. 11B, April 1978, p. 4997

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	CCC					
	DDD					
	EEE					

## FOREIGN PATENT DOCUMENTS

EEE						English Abstract		Translation. Readily Available		
FOREIGN PATENT DOCUMENTS										
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	FFFF									
	GGG									

## OTHER (Including in this order: Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

HHH	B.J. Lin, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 922, Optical/Laser Microlithography (1988), pp. 256-269				
IIIR	G.W.W. Stevens, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol.21 008, pp. 68-72				
JJJS	S. Owa et al., "Immersion Lithography; its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003				
KKK	S. Owa et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 (2003)				
LLL	Nikon Precision Europe GmbH, "Investor Relations - Nikon's Real Solutions", May 15, 2003				
MMM	H. Kawata et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-36				
NNN	J.A. Hoffnagle et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B., Vol. 17, No. 6, November/December 1999, pp. 3306-3309				
OOO	B.W. Smith et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003				
PPP	H. Kawata et al., "Fabrication of 0.2µm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens", Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177				
QQQ	G. Owen et al., "1/8µm Optical Lithography", J. Vac. Sci. Technol. B., Vol. 10, No. 6, November/December 1992, pp. 3032-3036				
RRR					
SSS					
TTT					
UUU					
VVV					
WWW					
XXX					
YYY					

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PTO RECEIPT Attorney Docket: 081468-0306781

Atty: Jack Barufka/JPH:K.S. Hines

Appln. No: / ,000 Date: November 12, 2003

Inventor(s): Joeri LOF *et al.*

Title: LITHOGRAPHIC APPARATUS AND DEVICE  
MANUFACTURING METHOD

☐ Preliminary Amendment ☒ Application Data Sheet  
☐ Appendix ☒ Utility/Design/Provisional

☒ 19 No. of Pages Application (Spec + Claim(s) + Abstract)

☐ No. of Pages Separate Power of Attorney

☒ 47 No. of Numbered Claims Only

☐ Declaration ( of pages)

☐ Assignment ☐ Cover Sheet

☒ 1 No. of Priority Documents

☒ 2 No. of Sheets of Drawings (Fig(s) 1-4)

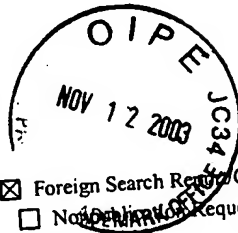
☐ IDS ☐ Appendix for Cited Appl(s)

☒ PTO-1449 ☒ Cited Documents

\$            Total Fee Charged to Deposit Account 033975

Other: Submission of Priority Document

CURRENT DUE DATE:



☒ Foreign Search Report/OA  
☐ Nonpublication Request

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CDC-285A 7/96

PTO RECEIPT Attorney Docket: 081468-0306781

Atty: Jack Barufka/JPH:K.S. Hines

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10/705805



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